

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Kwang Su Choe, et al.

Examiner: Marianne L. Padgett

Serial No.: 10/674,647

Art Unit: 1762

Filed: September 30, 2003

Docket: YOR920030293US1 (16818)

For: THIN BURIED OXIDES BY LOW-DOSE
OXYGEN IMPLANTATION INTO MODIFIED
SILICON

Dated: June 1, 2009

Confirmation No: 4796

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

RESPONSE UNDER 37 C.F.R. § 1.111


Sir:

In response to the Office Action dated March 17, 2009, please consider the following amendments and remarks with respect to the above referenced application.

CERTIFICATE OF ELECTRONIC FILING

I hereby certify that this correspondence is being deposited with the United States Patent & Trademark Office via Electronic Filing through the United States Patent and Trademark Office e-business website, on June 1, 2009.

Dated: June 1, 2009



Leslie S. Szivos